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A wide-range topological thermometer with Ta₂Pd₃Te₅: from power-law response to application prospects

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In recent decades, there has been a persistent pursuit of applications for surface/edge states in topological systems, driven by their dissipationless transport effects. This work demonstrates the remarkable properties of the topological material Ta₂Pd₃Te₅, as a thermometer. At low temperatures, it shows a power-law correlation in temperature-dependent resistance, while behaving like a semiconductor at high temperatures. This dual behavior effectively mitigates the issue of infinite resistance in semiconductor thermometers at ultra-low temperatures, making it ideal for millikelvin-range refrigerators. Through chemical doping, thickness adjustment, and gate voltage control, its performance can be finely tuned, and can also enable micron-scale local temperature measurement from millikelvin to room temperature. Furthermore, this thermometer exhibits excellent temperature sensitivity and resolution, and can be fine-tuned to show small magnetoresistance. In summary, the Ta₂Pd₃Te₅-based thermometer, also referred to as a topological thermometer, demonstrates considerable potential for broad-temperature-range detection and merits further investigation and optimization.

Topological materials and physics have become a prominent field in condensed matter physics due to the emergence of various novel physical phenomena and the dissipationless transport features of topological surface/edge states^{1–3}. The potential applications of these topological properties, such as topological electronic devices^{4–7} and topological quantum computations^{8,9}, continue to be actively pursued. However, they either require further research to fully understand their capabilities or seem not to have yet demonstrated significant technological advantages compared to current technologies. In this context, a novel property of topological materials has been developed as a resistance thermometer for wide-range thermometry, representing a notable application for topological materials and potentially referred to as a topological thermometer.

The resistance thermometer, with its ability to measure a wide temperature range from millikelvin temperatures or below to room temperature, has gained increasing significance in the field of low-temperature physics. It plays a crucial role in efficiently studying successive phase

transitions, particularly those involving ultra-low-temperature exotic quantum states such as the fractional quantum Hall effect⁸, anomalous quantum Hall effect¹⁰, quantum spin liquid¹¹, quantum phase transitions^{12,13}, non-Abelian anyons¹⁴, and quantum states for quantum computing¹⁵, among others. Although refrigerators supporting sub-mK temperatures or lower have been successfully developed for various types of experimental measurements^{16–18}, their widespread adoption is challenging due to the complex operations and inherent disadvantages. One important disadvantage is that thermometers such as the He-3 melting pressure thermometer^{17,19}, Coulomb blockade thermometry^{16,20}, noise thermometry^{18,21}, and pulsed platinum NMR thermometer^{18,22,23}, host complex preparation requirements and most of them are quite time-consuming for measuring ultra-low temperatures. On the contrary, semiconductor thermometers are extensively employed at low temperatures due to their high sensitivity and active feedback temperature control, as depicted in Fig. 1a. The semiconducting feature with a negative temperature

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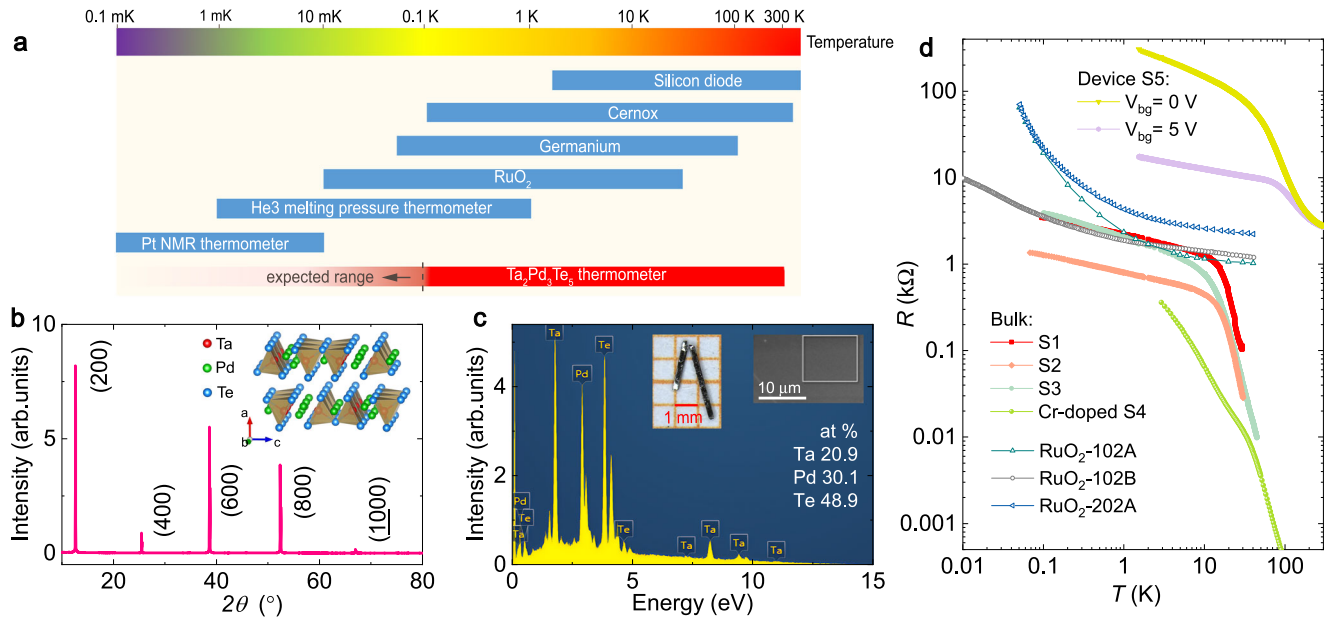


Fig. 1 | Properties of Ta₂Pd₃Te₅. **a** The temperature range application for various low-temperature thermometers. The blue bars represent commonly used commercial thermometers, while the left part of the dashed line in the Ta₂Pd₃Te₅ thermometer signifies its the predictable ability and requires further measurements. The temperature color bar scale is logarithmic. **b** Typical XRD spectrum for the (100) facet of the single crystal. The inset displays the structure of the van der Waals

material with quasi-one-dimensional (quasi-1D) Ta-Te chains. **c** Typical EDS spectra, which were collected on the flat clean surface, are shown in the right inset. The left inset displays the photomicrograph of the crystals. **d** Electrical resistance of pristine undoped and Cr-doped Ta₂Pd₃Te₅ bulk thermometers (S1–S4), thin-film Ta₂Pd₃Te₅ thermometer (S5), and RuO₂ thermometers²⁶.

coefficient causes the resistance (R) to increase exponentially as the temperature (T) decreases. Nevertheless, the giant resistance exhibited at millikelvin temperatures renders most semiconductor thermometers unusable. Consequently, temperature detection ranges and R – T curves of thermometers can be modulated by various methods, including controlling the ratio of conducting zirconium nitride to insulating zirconium oxide for Cernox thermometers²⁴, and adjusting the RuO₂ grain size and the volume fraction of RuO₂ in the paste for RuO₂ thermometers²⁵. However, the capability to detect a broad temperature range is often constrained by limited measurement ranges, as seen in conventional thermometers like the RuO₂ thermometer, which typically operates between 10 mK and 40 K²⁶, and Cernox thermometers, which cover a range of 100 mK to 420 K²⁶. A common strategy employs multiple thermometers to cover diverse temperature ranges; however, different thermometers may exhibit slight inconsistencies in overlapping ranges. Consequently, developing a resistance thermometer that diverges from traditional semiconducting properties is essential, not only to push the limits of ultra-low temperature measurement but also to expand the overall temperature range. Such a thermometer would also advance research in successive phase transitions and temperature-dependent physical phenomena.

In this work, a topological insulator Ta₂Pd₃Te₅^{27–29} is chosen as the main material for the potential resistance thermometer. The material exhibits several compelling properties, including excitonic insulator states^{30–32} and edge states^{28,31,33,34}, which may contribute to the following practical applications. For example, the edge states of the film can be utilized in fabricating an interfering Josephson diode³⁴, which exhibits high diode efficiency at small magnetic fields (B) with ultra-low power consumption. On the other hand, its R – T curve at low temperature deviates from a high-temperature semiconductor behavior ($R \propto e^{\Delta/2k_B T}$) and instead shows a power-law behavior ($R \propto T^{-\alpha}$), where Δ is the semiconductor gap, k_B is the Boltzmann constant, and α is a power-law coefficient. The power-law behavior may originate from the Luttinger liquid (LL) of edge states at low temperatures^{28,35}, leading to a slower rate of resistance increase with decreasing temperature compared to the typical observation in a

semiconductor. Hence, the unique properties of a Ta₂Pd₃Te₅ thermometer can be utilized for detecting lower temperatures, while retaining the traditional semiconductor behavior for high-temperature detection. The observed transport properties may be attributed to the coexistence of edge states and a fully gapped excitonic insulator phase, while a trivial semimetal/metal exhibits conventional metallic R – T behavior and cannot function as a reliable thermometer for ultra-low temperature measurements. In addition, the relative ease of fabrication and stable performance across various thicknesses further positions the Ta₂Pd₃Te₅ thermometer as a preferred option over other LL systems^{36–40}, like carbon nanotubes³⁶.

Results

Characterization of Ta₂Pd₃Te₅

Before introducing the Ta₂Pd₃Te₅ thermometer, we first characterize the Ta₂Pd₃Te₅ single crystal. In Fig. 1b, the typical X-ray diffraction (XRD) data exhibit good spectra for the (100) facet of the single crystal, indicating the high quality of our samples. Fig. 1c displays a typical pattern of the energy-dispersive X-ray spectroscopy (EDS), and the chemical composition is Ta:Pd:Te = 2.09:3.00:4.87 (Ta:Pd:Te:Cr = 1.77:3.00:4.99:0.01) for the pristine undoped (chromium-doped) compounds. Despite the low content of chromium in Cr-doped samples, their distinct transport properties compared to pristine samples will indicate the effective Cr-doping, as shown in Supplementary Figs. S2–S4. Bulks and devices are synthesized or fabricated using the same method as described in the literatures^{28,29}.

Transport measurements are conducted to investigate the properties of Ta₂Pd₃Te₅ thermometers (Fig. 1d). The temperature-dependent resistance of bulk samples S1, S2, and S3 exhibits significant deviation from typical semiconductor behavior below 20 K, with slight variations in observed values and characteristics across samples attributable to differences in size and quality. Notably, this deviation is integrally shown in device S5 over a wide temperature range, leading to a power-law behavior at low temperatures. The power-law behavior can also be observed from dV/dI – V_{bias} curves, and the conductance can be well scaled, suggesting the presence of LL stemming from edge states²⁸. This type of LL has also been observed in

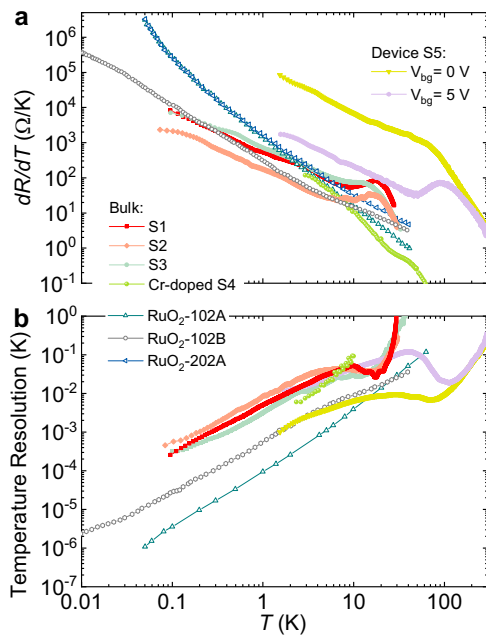


Fig. 2 | Temperature sensitivity and resolution. Temperature sensitivity (a) and resolution (b) for Ta₂Pd₃Te₅ thermometers and RuO₂ thermometers. The data for RuO₂ thermometers originate from literatures^{26,42}.

other 2D systems with edge states, such as quantum spin Hall insulators^{37,38} and quantum Hall systems^{39,40}. The power-law behavior provides a notable advantage, as it exhibits a much lower rate of resistance increase with decreasing temperature compared to the majority of commercial semiconductor thermometers^{26,41} (Fig. 1d or Supplementary Fig. S1). For instance, commercial thermometers like RuO₂, germanium RTD, and Cernox can easily exceed 1 MΩ at temperatures below 100 mK, rendering them unusable at lower temperatures. Among these conventional semiconductor thermometers, RuO₂-102B⁴² exhibits the smallest resistance at ultra-low temperature (Fig. 1d) and shows potential for lower temperature detection. Compared to RuO₂-102B, the Ta₂Pd₃Te₅ bulk thermometer easily possesses a much smaller increase rate of resistance at low temperature due to the small $\alpha \sim 0.21, 0.21,$ and 0.31 for samples S1, S2, and S3, respectively. It also hosts a larger increase rate of resistance at high temperatures due to its excellent semiconductor behavior, in comparison to most RuO₂ thermometers, suggesting its high sensitivity at high temperatures. Therefore, it is an ideal candidate for wide-range temperature detection, particularly extending to ultra-low temperatures. The small Cr-doped Ta₂Pd₃Te₅ bulk shows low resistance at high temperatures, but it displays an approximate power-law behavior with a large α value of 1.55 (see Fig. 1d and Supplementary Fig. S2). This behavior suggests a comparable detection limit to RuO₂-102A and RuO₂-202A, because its projected resistance approaches the MΩ range at ~ 10 mK (see Supplementary Table S1).

Temperature sensitivity and resolution

The temperature sensitivity of Ta₂Pd₃Te₅ thermometers is further studied in Fig. 2a. The temperature sensitivity, which describes the resistance sensitivity of the thermometer to temperature, is typically small for semiconductor thermometers at high temperatures and significantly large at low temperatures. For bulk Ta₂Pd₃Te₅ thermometers, the sensitivity varies from ~ 10 (20 K) to $4 \times 10^4 \Omega/K$ (0.1 K), comparable to that of the RuO₂-102B⁴². Their sensitivity remains substantial in the crossover region between power-law and semiconductor regimes but declines rapidly above 20 K as the system transitions progressively into a semiconductor state. In addition, the Cr-doped Ta₂Pd₃Te₅ thermometer also shows low sensitivity at high temperatures and high sensitivity at low temperatures (see Fig. 2a and

Supplementary Fig. S2), indicating its better applicability at relatively low temperatures. Moreover, the thin-film thermometer (device S5) demonstrates higher resistance and sensitivity across a wider temperature range when compared to bulk thermometers and RuO₂ thermometers. These results demonstrate its suitable sensitivity for detecting a wider range of temperatures.

The temperature resolution of Ta₂Pd₃Te₅, defined as the minimum detectable temperature change during measurement⁴¹, is also illustrated in Fig. 2b. This parameter can be expressed as $\Delta T = \Delta R / (dR/dT)$ ²⁶, where it depends on both the temperature sensitivity (dR/dT) and the instrument resistance resolution ΔR . The resolution is determined not only by the voltage noise level (U_n) of the measuring instrument but also by the applied current excitation (I_{ac}), with resistance resolution $\Delta R = U_n / I_{ac}$. In the case of instrument noise, several techniques, such as optimized filters, can be utilized to diminish system noise and improve measurement precision. Regarding the excitation, the application of a relatively large excitation in the circuit can also improve the measurement resolution. For instance, in our systems, multilevel filters are used to minimize the instrument noise U_n , to as low as ~ 10 nV, such as π filters in the measuring box, RC filters at the mixing chamber. The activation energy caused by applied current excitation I_{ac} is slightly lower than the thermal excitation energy at the given temperature, ensuring no noticeable Joule heating effect. Moreover, the lock-in technique (LI5650, NF Corporation, which offers the high precision measurement capabilities) is applied to provide the excitation and measure the thermometers. Compared to RuO₂-based thermometers, Ta₂Pd₃Te₅-based thermometers exhibit slightly lower temperature resolution at low temperatures (where smaller values indicate higher resolution, as shown in Fig. 2b), which maybe stem from the conservative estimation of ΔR . For bulk thermometers such as sample S1 at 0.1 K, the temperature resolution and precision (a ratio of temperature resolution to temperature) are lower than 0.3 mK and 0.3%, respectively. The thin-film thermometer S5 exhibits relatively high temperature resolution, highlighting its effectiveness for measuring temperatures across a wide range. Similarly, the Cr-doped sample S4 exhibits temperature resolution comparable to that of the pristine bulk sample at low temperatures, as shown in Fig. 2b and Supplementary Fig. S2. In summary, Ta₂Pd₃Te₅ film thermometers not only demonstrate exceptional capabilities for detecting a wide range of temperatures but also exhibit excellent temperature sensitivity and resolution.

Magnetoresistance

The Ta₂Pd₃Te₅ thermometers are subsequently calibrated under a magnetic field up to 31 T. The response of the thermometers to a magnetic field is also a crucial property, and their small magnetoresistance is beneficial for their applications. In Fig. 3a, the magnetoresistance [$MR = R(B)/R(0) - 1$] of sample S2 could reach 29% (10%) at 31 T (9 T) and 1.8 K, consistent with the previously reported literature⁴³. The MR is much smaller than that of many semimetals^{44–48} and the germanium thermometer at low temperatures^{26,49}. The temperature display error of the thermometer due to the presence of a magnetic field can be described by a ratio $\Delta T/T$ ⁴¹ shown in Fig. 3b, where $\Delta T = |T(B) - T(0)|$. The value of $\Delta T/T$ at 1.8 K and 31 T is slightly over 70%, indicating a not small value compared to general thermometers. If considering a magnetic field strength of 9 T, it is estimated that $\Delta T/T$ (9 T) is 41% at 1.8 K and 3.6% at 10.5 K, suggesting that the magnetic effect of the Ta₂Pd₃Te₅ thermometer can be considered negligible above 10 K.

In addition, angle-dependent magnetoresistance measurements are performed to study whether there is a small magnetoresistance at specific angles. In Fig. 3c, d, MR at 1.8 K for different angle θ shows a similar situation, with the smallest MR occurring at the perpendicular magnetic field B_{\perp} , which is the most commonly used direction in this material ($B_{\perp} || a$ axis). MR at lower temperatures is further measured in sample S1, leading to slightly larger MR and $\Delta T/T$ in Fig. 3e, f.

The magnetoresistance of Ta₂Pd₃Te₅ thermometers can be effectively reduced by adjusting the Fermi level, for example, through chemical doping or voltage gating. The Cr-doped samples with higher carrier density exhibit a significant reduction in MR, with $\Delta T/T$ decreasing to as low as $\sim 3\%$ at 2 K

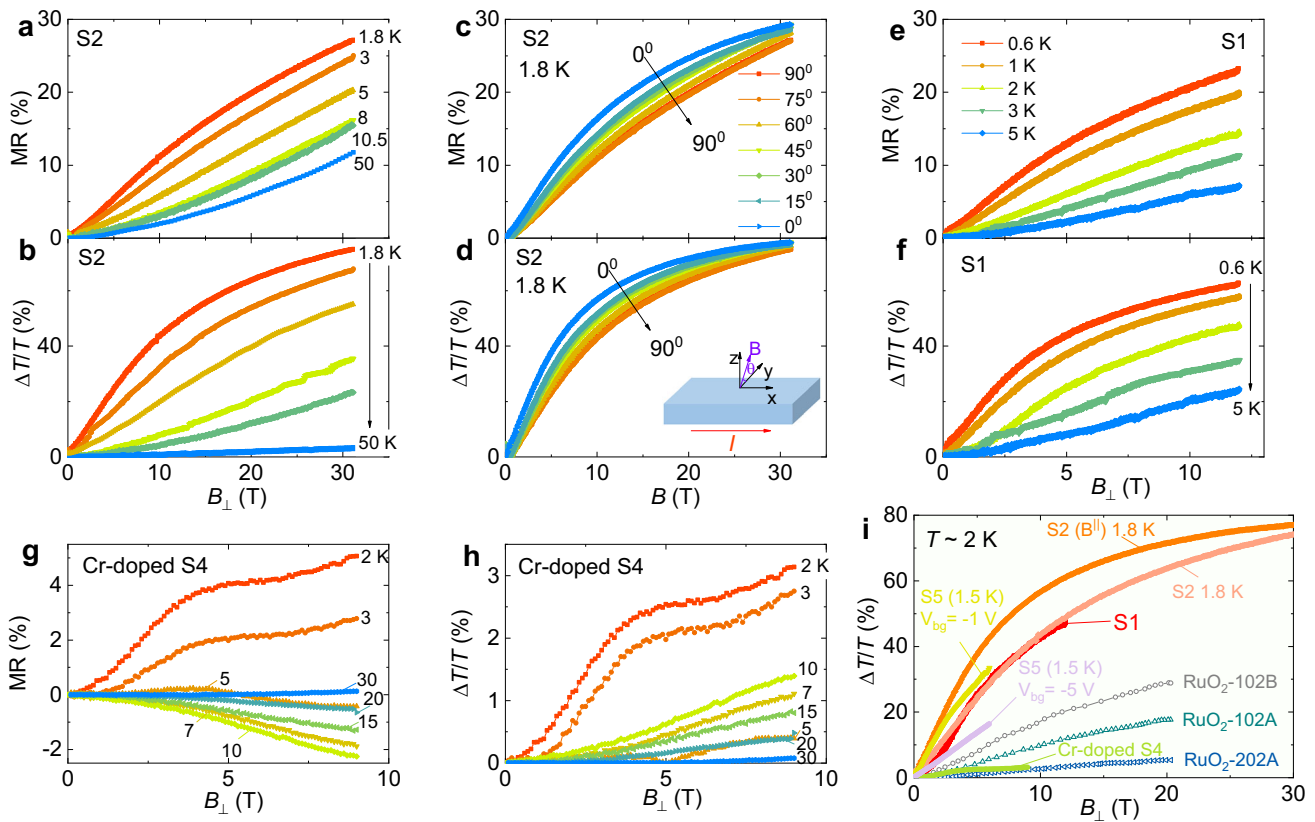


Fig. 3 | Magnetoresistance of Ta₂Pd₃Te₅ thermometers. MR of samples S2 (a), S1 (e), and Cr-doped S4 (g) at different temperatures. MR of the Cr-doped sample S4 is much smaller. c Slight anisotropic MR of sample S2. The change of temperature [$\Delta T = |T(B) - T(0)|$] under magnetic fields for samples S2 (b, d), S1 (f) and S4 (h). $\Delta T/T$

below 3 K for samples S4 and S5 is approximately estimated based on the extended power-law behavior of $R - T$ curves. i Summary of $\Delta T/T$ (~ 2 K) under applied magnetic fields for Ta₂Pd₃Te₅ and commercial RuO₂²⁶ thermometers.

and 9 T, as shown in Fig. 3g, h, and Supplementary Figs. S3 and S4. This observation is further supported by additional samples S6 and S7 (refer to Supplementary Fig. S3). Its $\Delta T/T$ under a magnetic field can be comparable to that of the RuO₂-202A²⁶ (Fig. 3i), suggesting its strong applicability under magnetic fields and indicating its potential to replace the RuO₂-202A and several resistance thermometers at ultra-low temperatures. The reproducible measurements performed in three Cr-doped Ta₂Pd₃Te₅ thermometers highlight their high stability (see Supplementary Fig. S3). The thin-film thermometer also shows greater magnetoresistance than RuO₂ thermometers²⁶ (Fig. 3i), but its magnetoresistance can be greatly reduced when deviating from the charge neutral point (CNP), similar to the Cr-doped case.

Modulation of thin-film devices

To expand the thermometry range of Ta₂Pd₃Te₅ thermometers, the thin-film thermometer is a favorable option due to its relatively high resistance at high temperatures, suitable α at low temperatures, and excellent temperature sensitivity/resolution. The bulk thermometer, while performing well for ultra-low temperatures, seems not suitable for use above 30 K due to its low resistance and sensitivity, as illustrated in Figs. 1 and 2. Therefore, two methods are employed to overcome this shortcoming: thickness modulation and gate modulation. First, the thickness-dependent $R - T$ curves at CNP are shown in Fig. 4a. At high temperatures, the large resistance ($> \sim 100 \Omega$) of the sensor is observed for thickness < 100 nm, ensuring relatively high sensitivity. Thus, thin-film thermometers can readily extend the working temperature range up to 300 K. As for enhancing the measurement limit for ultra-low temperatures, there are two important factors to our knowledge. One contributing factor is the suitable transition temperature (T_1) that deviates from the typical behavior observed in semiconductors.

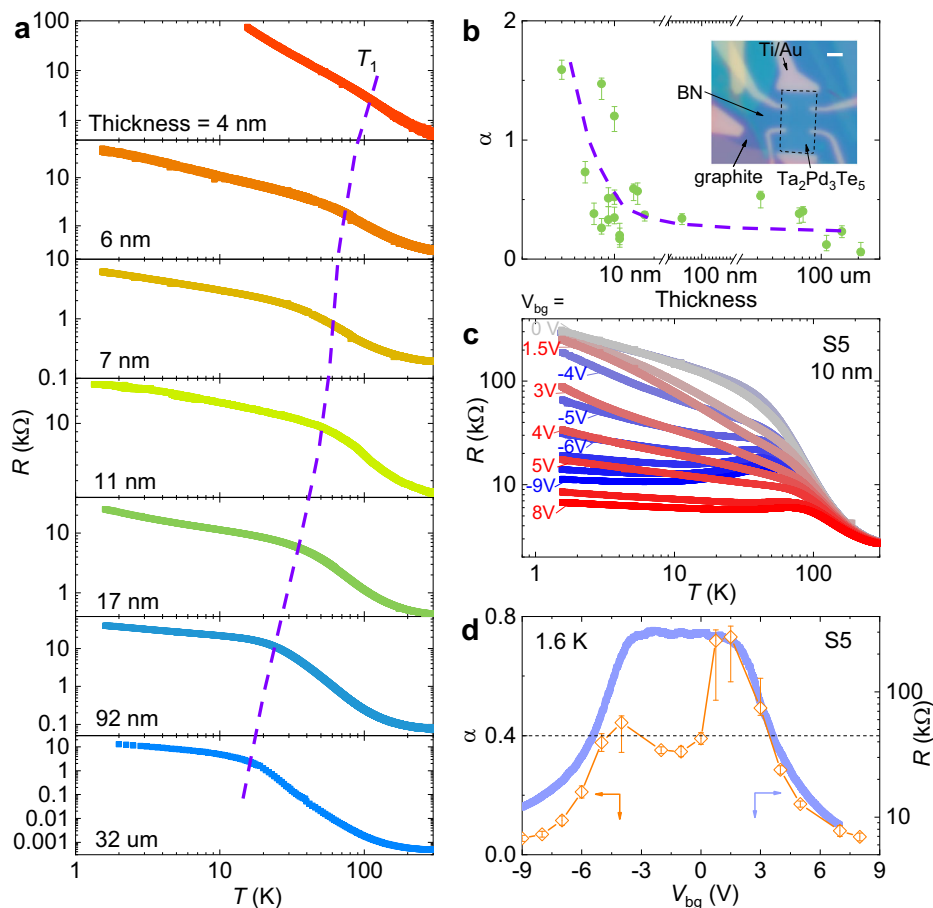
In Fig. 4a, T_1 gradually decreases (indicated by the violet dashed line) with increasing thickness of Ta₂Pd₃Te₅ films, which has been previously discussed in our prior literature²⁸. Another factor is the relatively small power-law coefficient α . Therefore, thin-film thermometers with an optimal thickness range (10 nm $<$ thickness $<$ 100 nm) exhibit excellent and stable performance, characterized by suitable α (Fig. 4b), resistance, and T_1 . Moreover, their fabrication and application for a wide range of temperature detection can be easily achieved.

On the other hand, gate or carrier density modulation is an effective method for tuning the $R - T$ curves of a film thermometer, particularly at low temperatures. For example, for sample S5, when the back gate voltage V_{bg} exceeds -4 or 5 V (using boron nitride as an insulator medium for the gate), as shown in Fig. 4c, the resistance gradually increases or even decreases as the temperature reduces, following a departure from the semiconducting behavior. Consequently, it begins to deviate from the favorable power-law behavior, although it may reenter an apparent power-law behavior at lower temperatures. The relatively good power-law behavior is observed within the large gating range (-4 V $<$ V_{bg} $<$ 5 V) in Fig. 4c. In Fig. 4d, α demonstrates similar variations to resistance in response to changes in V_{bg} . The reduction of α at the conduction band is consistent with the results in the SiO₂ gate-tuned α ²⁸. Therefore, by attaining an appropriate $R - T$ curve and α near the CNP, it becomes possible to enable wide-range temperature detection (see Supplementary Table SI) and micron-scale localized temperature sensing.

Discussion

Before reaching a conclusion about this Ta₂Pd₃Te₅ thermometer, it is important to clarify several key aspects related to the low-temperature experiments. Heat capacity contributions arising from different

Fig. 4 | Thickness and gate-dependent resistance of Ta₂Pd₃Te₅. **a** Thickness dependence of R - T curves in Ta₂Pd₃Te₅ at CNP. The violet dashed line is the guideline for T_1 . **b** α as a function of thickness. The inset shows a typical Ta₂Pd₃Te₅ device, with the white scale bar corresponding to 2 μ m. The violet dashed line serves as the guideline for thickness-dependent α . **c** Temperature-dependent resistance at different V_{bg} for device S5. The relatively large resistance of device S5 at low T is primarily attributed to its small cross-sectional area. **d** V_{bg} -dependent resistance and α in sample S5. This device with $\alpha < 0.4$ seems more suitable to detect lower temperatures (Supplementary Table S1).



mechanisms in materials necessitate tailored cooling strategies at different temperature ranges. Taking copper⁵⁰, a commonly used material in low-temperature experiments, as an example, phonon heat capacity ($C_p \propto T^3$) dominates above 1 K, whereas electronic heat capacity ($C_p \propto T$) becomes dominant below ~ 1 K. At even lower temperatures (below ~ 1 mK), nuclear spin heat capacity begins to dominate the thermal properties. These indicate the complexity and difficulty of experiments conducted at millikelvin temperatures. Consequently, semiconductor-type thermometers face significant challenges at millikelvin temperatures, owing to both their near-infinite electrical resistance and the fundamental difficulty in achieving sufficient electron temperature reduction. It should be noted that the actual electron temperature of the sensor/chip in the refrigerator easily exceeds the millikelvin base temperature⁵¹, primarily due to parasitic radiofrequency heating and self-heating effects. The former can be mitigated through multi-stage filtering, while the latter can be partially reduced by lowering the excitation current.

Furthermore, beyond external considerations, for a resistance thermometer to operate effectively at low temperatures, it must first maintain a resistance below the 1 M Ω level. In Table 1, Supplementary Table S1 and Fig. S1, it is evident that general commercial semiconductor thermometers, such as Cernox, germanium RTD, RuO₂-102A, and RuO₂-202A, have extensional resistances much larger than 1 M Ω below ~ 10 mK, indicating their limited ability to effectively detect lower temperatures. Subsequently, RuO₂-102B was developed through the control of the proportion of RuO₂, paste, and other components²⁵, resulting in its resistance deviating distinctly from exponential response (Fig. 1d) at low temperatures^{42,51}. Consequently, this form of RuO₂ enables temperature detection down to lower temperatures (Supplementary Table S1), although its upper detection limit is still confined to about 40 K. On the contrary, Cernox exhibits high temperature sensing

capability, but its low-temperature operational limit remains relatively high above 0.1 K²⁶. In addition, although Ta₂Pd₃Te₅ shows promising potential at low temperature due to its effective suppression of exponentially increasing resistance via power-law behavior, systematic characterization below 0.1 K remains to be conducted under specially optimized refrigeration configurations. This limitation arises because the electron temperature in our current cryogenic system cannot be effectively and timely cooled to such low temperatures, as shown in Supplementary Fig. S7.

Table 1 summarizes the performance characteristics of conventional low-temperature thermometers and Ta₂Pd₃Te₅-based thermometers. This material offers unique advantages for micron-scale local temperature measurements in 2D materials and nanodevices - a critical niche where conventional sensors face limitations. For instance, Cernox and RuO₂ thermometers are typically too bulky for such applications, while alternatives like Pt electrodes suffer from diminished sensitivity below 20 K. Moreover, the material demonstrates excellent measurement repeatability within 1 month (Supplementary Fig. S6), though extended-duration stability requires further evaluation in future commercial iterations. In addition, this thermometer exhibits three main limitations: (1) Pronounced MR in its pristine undoped form (Fig. 3i, Table 1); (2) Limited utility above 20 K for bulk samples due to rapidly declining sensitivity; (3) The gap remains between the current experimental results and commercial applications. A key challenge remains the scale-up of thin-layer sample production, particularly through sputtering techniques or alternative methods, while Cernox and RuO₂ have been commercialized and show excellent performance. In summary, although this class of topological thermometers demonstrates considerable potential for measuring a wider range of temperatures, further investigation is warranted to optimize their performance characteristics and fabrication processes.

Table 1 | Summary of properties for typical ultra-low temperature resistance thermometers

Thermometers	Suggested T-range	$\Delta T/T$ (2 K, 9 T)	Performance in B	R-T curve
Bulk TPT	0.1–20 K	40%	NS	PL+SC
Bulk Cr-TPT	0.1–20 K	3.1%	Good	PL+SC
Film TPT	0.1–300 K	>10%	Good (>10 K)	PL+SC
Cernox ²⁶	0.1–420 K	<6%	Good (>1 K)	SC
RuO ₂ -102B ²⁶	0.005–40 K	15%	NS	SC
RuO ₂ -102A ²⁶	0.05–40 K	~9%	Good	SC
RuO ₂ -202A ²⁶	0.05–40 K	2.5%	Good	SC
Ge RTD ²⁶	0.05–100 K	>60%	NS	SC

We abbreviate Ta₂Pd₃Te₅ as TPT, Cr-doped Ta₂Pd₃Te₅ as Cr-TPT, power law as PL, semiconductor as SC, and “not suggested” as NS. In column (Performance in B), we present the usage recommendations for TPT under high-B conditions, while the recommendations for other thermometers in B are obtained from the Lakeshore website²⁶. R-T curve of TPT includes the PL and SC behavior.

Methods

Sample preparation and characterization

Single crystals of Ta₂Pd₃Te₅ and Cr-doped Ta₂Pd₃Te₅ were synthesized using the self-flux method²⁹. The XRD data were collected by monochromatic Cu K_{α1} radiation, and the composition ratio of the crystals was analyzed by EDS. The Ta₂Pd₃Te₅ devices were fabricated using conventional nanofabrication technology²⁸.

Transport measurements

The electrical resistance measurements at low magnetic fields were performed in Oxford TeslatronPT cryostats and dilution refrigerators, using constant voltage measurement methods. The Cr-doped samples are measured in the Physical Property Measurement System in the public performance, using the constant current measurement method. The resolution of Cr-doped samples is only displayed at low temperatures, as the discontinuous excitation current is applied during this measurement, and its low-temperature resolution is closer to the low-temperature limit. The high-field magnetotransport measurements were also performed using a standard AC lock-in technique with a DC-resistive magnet (~31 T) at the China High Magnetic Field Laboratory (CHMFL) in Hefei.

Data availability

The data within this paper are available from the corresponding author.

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Author contributions

J.S. and Y.P.L. conceived and designed the experiment. Y.P.L. and A.Q.W. fabricated the devices with the assistance of G.Y., X.C.G., Z.Y.Z., and Y.H. Y.P.L. and A.Q.W. performed the transport measurements, supervised by T.Q., Z.W.D., G.T.L., F.M.Q., L.L., and J.S. S.Y.P. and J.L.Z. performed the high-field transport measurements. D.Y.Y. and Y.G.S. prepared Ta₂Pd₃Te₅ crystals. Z.J.W. provided the theoretical support. Y.P.L., A.Q.W. and J.S. wrote the manuscript with help from all other co-authors.

Competing interests

The authors declare no competing interests.

Additional information

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